Interpenetrating heterojunction photovoltaic cells based on C60 nano-crystallized thin films

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Supplementary Materials for Interpenetrating Heterojunction Photovoltaic Cells Based on C_{60}

Nano-Crystallized Thin Films

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Fig. S1. UV–Vis spectra of (a) C_{60} films formed with and without solvent spin-coating method and (b) C_{60} films formed with and without SVA method.



Fig. S2. SEM images of C_{60} nanocrystallized films treated by different time ((a) 0 min, (b) 30 min, (c) 45 min and (d) 60 min) by SVA method with EtOH.



Fig. S3. AFM images of C_{60} nanocrystallized films treated by different time ((a) 0 min, (b) 30 min, (c) 45 min and (d) 60 min) by SVA method with EtOH

Table

Parameter	C ₆₀ nanocrystallized films			
	CHCl ₃	CHCl ₃ SVA	$n - C_6 H_{14}$	EtOH SVA
	spin-coat		SVA	
FWHM (B)	0.42	0.54	0.24	0.78
Bragg Angle (θ) Primary peak	5.076	5.38	5.393	5.421
X-ray wavelength (λ)	1.54	1.54	1.54	1.54
Constant (K)	0.94	0.94	0.94	0.94
D _{SEM} (nm)	100~300	150~300	500	150
D _{XRD} (nm)	19.7	15.5	34.9	10.8
d-space (Å)	8.71	8.21	8.19	8.15

Table S1. Peak parameters used to calculate the mean crystalline size in films formed with solvent annealing using the Scherrer formula.

 D_{SEM} and D_{XRD} represent the mean crystal size and particle diameter size calculated from SEM and XRD patterns, respectively.